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(54) Title: MEASUREMENT TECHNIQUE FOR REFRACTIVE INDEX INHOMOGENEITY BETWEEN PLATES OF A LIGHT-GUIDE OPTICAL ELEMENT (LOE)

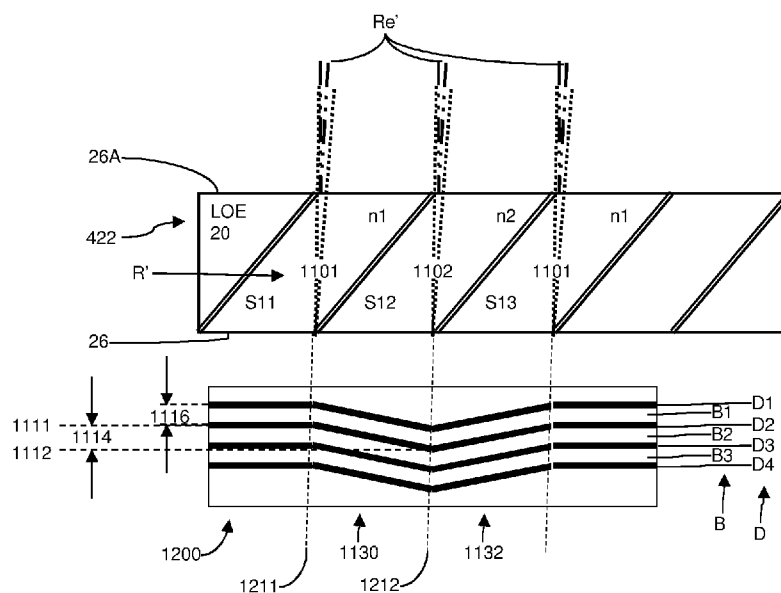


FIG. 11

(57) Abstract: A system and method for measuring refractive index inhomogeneity between plates of a Lightguide Optical Element (LOE) uses an innovative measuring technique based on a shearing interferometric technique conventionally used to observe interference and test the collimation of light beams. Another feature of the current implementation is an innovative method for analyzing the characteristics of the generated interferogram to characterize discrepancies between adjacent plates in an LOE.

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Measurement Technique for Refractive Index Inhomogeneity Between Plates of a Lightguide Optical Element (LOE)

FIELD OF THE INVENTION

5 The present invention generally relates to optical testing, and in particular, it concerns a non-contact measurement technique of refractive index differences.

BACKGROUND OF THE INVENTION

10 One of the manufacturing challenges in production of a Lightguide Optical Element (LOE) is achieving homogeneity of the refractive index. Inhomogeneity results in degradation in image quality. As rays cross the facets, particularly at large angles with respect to a normal to the facets, angular deviation will be introduced if the refractive indices of the individual plates are not sufficiently well matched.

15 SUMMARY

 According to the teachings of the present embodiment there is provided a method for measuring refractive index inhomogeneity including the steps of: projecting projected light onto a front surface of a lightguide, the lightguide including: a first pair of external surfaces parallel to each other, the external surfaces including the front surface and a back surface, and a set of coated
20 plates, the set of coated plates: parallel to each other, between the first pair of external surfaces, and at a non-parallel angle relative to the first pair of external surfaces, and each of the plates having a corresponding index of refraction, and capturing an interferogram image of an interference pattern to measure the refractive index inhomogeneity between the plates, the interference pattern between refracted/reflected light rays and externally reflected light, the refracted/reflected light rays
25 being the result of the projected light traversing, reflecting internally, and then exiting the lightguide via the front surface and the externally reflected light being the result of the projected light reflecting from the front surface.

In an optional embodiment, the projecting is at an oblique angle relative to the front surface. In another optional embodiment, the projecting is normal relative to the front surface. In another optional embodiment, the interferogram image corresponds to refractive index inhomogeneity between the indices of refraction of the plates.

5 In another optional embodiment, further including: determining deviation between one or more portions of the fringes and another one or more portions of the fringes, each of the portions corresponding to one or more of the plates, the deviation corresponding to refractive index difference (inhomogeneity) between the indices of refraction of the plates.

10 According to the teachings of the present embodiment there is provided a method for determining refractive index inhomogeneity including the steps of: providing an interferogram, the interferogram including one or more fringes, the interferogram generated by: projecting projected light onto a front surface of a lightguide, the lightguide including: a first pair of external surfaces parallel to each other, the external surfaces including the front surface and a back surface, and a set
15 of plates, the set of plates: parallel to each other, between the first pair of external surfaces, and at a non-parallel angle relative to the first pair of external surfaces, and each of the plates having a corresponding index of refraction, and capturing an interferogram image of an interference pattern to measure the refractive index inhomogeneity between the plates, the interference pattern between refracted/reflected light rays and externally reflected light, the refracted/reflected light rays being
20 the result of the projected light traversing, reflecting internally, and then exiting the lightguide via the front surface and the externally reflected light being the result of the projected light reflecting from the front surface, and determining deviation between one or more portions of the fringes and another one or more portions of the fringes, each of the portions corresponding to one or more of the plates, the deviation corresponding to refractive index inhomogeneity between the indices of
25 refraction of the plates.

In an optional embodiment, each of the portions of the fringes corresponds to one of the plates. In another optional embodiment, the deviation is between adjacent the plates. In another optional embodiment, the deviation is across multiple the plates. In another optional embodiment, the deviation is across all the plates.

30 In another optional embodiment, determining deviation includes determining how many fringe jumps are in the interferogram.

In another optional embodiment, further including a step of calculating a pass/fail metric based on the deviation.

In another optional embodiment, the deviation is determined using at least one technique selected from the group consisting of: analyzing the interferogram to determine axes of the
5 interferogram, rotating and/or transforming the interferogram, splitting the interferogram into N discrete signal arrays orthogonal to the fringes, whereby N is significantly larger than the number of facets in the LOE, and calculating a phase of signal arrays $n=1$ to N, by use of a phase extraction algorithm selected from the group consisting of: three or four bucket method, and wavelet transform.

10 In another optional embodiment, a pass/fail metric is derived from the deviation determined over an entirety of the interferogram, and then other pass/fail metrics are derived from deviations between adjacent the plates.

In another optional embodiment, the deviation is determined by: splitting the interferogram into N discrete signal arrays orthogonal to the fringes, calculating a phase of the signal arrays $n=1$
15 to N, by use of a phase extraction algorithm, and plotting the phase as a function of n and determining maximum phase difference between overall maxima and minima in the phase plot.

In another optional embodiment, the deviation is determined: using a portion of one of the fringes, doing a best fit extrapolation to the portion of one of the fringes, and comparing the extrapolation to another portion of the fringes.

20 In another optional embodiment, the deviation is determined by: extrapolating one of the fringes to generate an ideal fringe, calculating a departure of an actual one of the fringes from the ideal fringe.

In another optional embodiment, the projected light is collimated light that has been slightly
25 defocused. In another optional embodiment, the projected light is monochrome light. In another optional embodiment, the projected light is in the visible spectrum.

According to the teachings of the present embodiment there is provided a system for measuring refractive index inhomogeneity, the system including: a display source, collimating

optics, a lightguide including: a first pair of external surfaces parallel to each other, the external surfaces including the front surface and a back surface, and a set of plates, the set of plates: parallel to each other, between the first pair of external surfaces, and at a non-parallel angle relative to the first pair of external surfaces, and each of the plates having a corresponding index of refraction, and
5 a capture device deployed to capture an interferogram image of an interference pattern to measure the refractive index inhomogeneity between the plates, the interference pattern between refracted/reflected light rays and externally reflected light, the refracted/reflected light rays being the result of the projected light traversing, reflecting internally, and then exiting the lightguide via the front surface and the externally reflected light being the result of the projected light reflecting
10 from the front surface.

In an optional embodiment, the system further including a processing system containing one or more processors, the processing system being configured to determining deviation between one or more portions of the fringes and another one or more portions of the fringes, each of the portions corresponding to one or more of the plates, the deviation corresponding to refractive index
15 inhomogeneity between the indices of refraction of the plates.

According to the teachings of the present embodiment there is provided a system for determining refractive index inhomogeneity, the system including a processing system containing one or more processors, the processing system being configured to: process an interferogram, the
20 interferogram including one or more fringes, the interferogram generated by: projecting projected light onto a front surface of a lightguide, the lightguide including: a first pair of external surfaces parallel to each other, the external surfaces including the front surface and a back surface, and a set of plates, the set of plates: parallel to each other, between the first pair of external surfaces, and at a non-parallel angle relative to the first pair of external surfaces, and each of the plates having a
25 corresponding index of refraction, and capturing an interferogram image of an interference pattern to measure the refractive index inhomogeneity between the plates, the interference pattern between refracted/reflected light rays and externally reflected light, the refracted/reflected light rays being the result of the projected light traversing, reflecting internally, and then exiting the lightguide via the front surface and the externally reflected light being the result of the projected light reflecting
30 from the front surface, and determine deviation between one or more portions of the fringes and another one or more portions of the fringes, each of the portions corresponding to one or more of

the plates, the deviation corresponding to refractive index inhomogeneity between the indices of refraction of the plates.

According to the teachings of the present embodiment there is provided a non-transitory computer-readable storage medium having embedded thereon computer-readable code for measuring refractive index inhomogeneity, the computer-readable code including program code for: performing any of the above methods

According to the teachings of the present embodiment there is provided non-transitory computer-readable storage medium having embedded thereon computer-readable code for determining refractive index inhomogeneity, the computer-readable code including program code for: performing any of the above methods.

According to the teachings of the present embodiment there is provided computer program that can be loaded onto a server connected through a network to a client computer, so that the server running the computer program constitutes a processing system in a system according to any of the above disclosures.

BRIEF DESCRIPTION OF FIGURES

The embodiment is herein described, by way of example only, with reference to the accompanying drawings, wherein:

FIG. 1 illustrates a conventional prior art folding optics arrangement.

FIG. 2 is a side view of an exemplary light-guide optical element (LOE).

FIG. 3A and FIG. 3B illustrate a desired reflectance behavior of selectively reflecting surfaces.

FIG. 4 is a detailed sectional view of an array of selectively reflective surfaces that couple light into a substrate, and then out into the eye of a viewer.

FIG. 5 illustrates an example of LOEs embedded in a standard eyeglasses frame.

FIG. 6 illustrates a method for fabricating an array of selectively reflecting surfaces.

FIG. 7 is further details of a method for fabricating an array of selectively reflecting surfaces.

FIG. 8 is a sketch of an exemplary portion of testing for an LOE

FIG. 9 is a high-level side-view sketch of an exemplary test setup.

5 FIG. 10A is a side-view sketch of how fringes are formed.

FIG. 10B is a detailed sketch of interference.

FIG. 11 is a sketch of producing an overall pattern for various regions of the LOE.

FIG. 12 is a photograph of a good fringe pattern.

FIG. 13 is a photograph of a bad fringe pattern.

10 FIG. 14 is a photograph of a really bad fringe pattern.

FIG. 15 is a high-level partial block diagram of an exemplary system configured to implement the processing module of the present invention.

ABBREVIATIONS AND DEFINITIONS

15 For convenience of reference, this section contains a brief list of abbreviations, acronyms, and short definitions used in this document. This section should not be considered limiting. Fuller descriptions can be found below, and in the applicable Standards.

1D – one-dimensional

2D – two-dimensional

20 CCD – charge coupled device

CRT - cathode ray tube

DMD - digital micro-mirror device

EMB - eye-motion-box

FOV - field-of-view

HMD - head-mounted display

HUD - head-up display

LCD - liquid crystal display

5 LCoS - liquid crystal on silicon

LED - light emitting diode

LOE - light-guide optical element

OLED - organic light emitting diode array

OPL - optical path length

10 SLM - spatial light modulator

TIR - total internal reflection

DETAILED DESCRIPTION

The principles and operation of the system according to a present embodiment may be better
15 understood with reference to the drawings and the accompanying description. A present invention
is a system and method for measuring refractive index inhomogeneity between plates of a
Lightguide Optical Element (LOE). An innovative measuring technique is based on the well-
known shearing interferometric technique conventionally used to observe interference and test the
collimation of light beams. Another feature of the current implementation is an innovative method
20 for analyzing the characteristics of the generated interferogram to characterize discrepancies
between adjacent plates in an LOE.

One of the manufacturing challenges in production of an LOE is achieving homogeneity of
the refractive index. Inhomogeneity results in degradation in image quality. As rays cross the
facets, particularly at large angles with respect to a normal to the facets, angular deviation will be
25 introduced if the refractive indices of the individual plates are not sufficiently well matched.

Basic technology – FIG. 1 TO FIG. 7

FIG. 1 illustrates a conventional prior art folding optics arrangement, wherein the substrate **2** receives light from a display source **4**. The display is collimated by collimating optics **6**, e.g., a lens. The light from the display source **4** is coupled into substrate **2** by a first reflecting surface **8**, in such a way that the main ray **11** is parallel to the substrate plane. A second reflecting surface **12** couples the light out of the substrate and into the eye of a viewer **14**. Despite the compactness of this configuration, this configuration suffers significant drawbacks. In particular, only a very limited FOV and Eye Motion Box (EMB) can be achieved.

Refer now to FIG. 2 is a side view of an exemplary light-guide optical element (LOE). To alleviate the above limitations, an array of selectively reflecting surfaces can be used, fabricated within a light-guide optical element (LOE). The first reflecting surface **16** is illuminated by a collimated display light ray (incoming light ray beams) **18** emanating from a light source (not shown) located behind the device. For simplicity in the current figures, only one light ray is generally depicted, the incoming light ray **18** (also referred to as the “beam” or the “incoming ray”). Other rays of incoming light, such as beams **18A** and **18B** may be used to designate edges of the incident pupil, such as a left and right edge of an incoming light pupil. Generally, wherever an image is represented herein by a light beam, it should be noted that the beam is a sample beam of the image, which typically is formed by multiple beams at slightly differing angles each corresponding to a point or pixel of the image. Except where specifically referred to as an extremity of the image, the beams illustrated are typically a centroid of the image.

The reflecting surface **16** is typically 100% reflecting (full mirror) and reflects the incident light from the source such that the light is trapped inside a lightguide **20** by total internal reflection. The lightguide **20** is also referred to as a “planar substrate” and a “light-transmitting substrate”. The lightguide **20** includes at least two (major) surfaces parallel to each other, shown in the current figure as a first (back, major) surface **26** and a second (front, major) surface **26A**. Note that the designation of “first” and “second” with regard to the major surfaces (**26**, **26A**) is for convenience of reference. Coupling-in to the lightguide can be from various surfaces, such as the front, back, side edge, or any other desired coupling-in geometry.

Incoming light ray **18** enters the substrate at a proximal end of the substrate (right side of the figure). Light propagates through the lightguide and one or more facets, normally at least a

plurality of facets, and typically several, more than 3 or 4 facets, toward a distal end of the lightguide (left side of the figure). Light propagates through the lightguide in both an initially reflected direction **28** of propagation, and another direction **30** of propagation.

The trapped light propagates through the lightguide, reflecting off the internal surfaces of the substrate **20** and traversing an array of selectively reflecting surfaces **22**. The selectively reflecting surfaces **22** are typically partially reflecting coupling-out facets, each of which couples a portion of the light out of the substrate into the eye **24** of a viewer

Internal, partially reflecting surfaces, such as selectively reflecting surfaces **22** are generally referred to in the context of this document as “facets”. For augmented reality applications, the facets are partially reflecting, allowing light from the real world to enter via front surface **26A**, traverse the substrate including facets, and exit the substrate via back surface **26** to the eye **24** of the viewer. The partial reflecting of the facets also allows a portion of the propagating light to continue propagating to subsequent facets. The internal partially reflecting surfaces **22** generally at least partially traverse the lightguide **20** at an oblique angle (i.e., neither parallel nor perpendicular) to the direction of elongation of the lightguide **20**. Partial reflection can be implemented by a variety of techniques, including, but not limited to transmission of a percentage of light, and/or use of polarization.

FIGS. 3A and 3B illustrate a desired reflectance behavior of selectively reflecting surfaces. In FIG. 3A, the ray **32** is partially reflected from facet **34** and coupled out **38** of the substrate **20**. In FIG. 3B, the ray **36** is transmitted through the facet **34** without any notable reflection.

FIG. 4 is a detailed sectional view of an array of selectively reflective surfaces that couple light into a substrate, and then out into the eye of a viewer. As can be seen, a ray **18** from the light source **4** impinges on the first reflecting surface **16** and reflected ray **42** is coupled into the substrate by total internal reflection. The trapped ray is gradually coupled out from the substrate by the other two exemplary partially reflecting surfaces **22** at the points **44**. The coating characteristics of the first reflecting surface **16** is not necessarily similar to that of the other reflecting surfaces **22**, **46**. This coating can be fully reflective, or a beam-splitter, either metallic, dichroic or hybrid metallic-dichroic.

FIG. 5 illustrates an example of LOEs **20a/20a'** and **20b** embedded in a standard eyeglasses frame **107**. The display source **4**, and the folding and the collimating optics **6** are assembled inside the arm portions **112** of the eyeglasses frame, just next to LOE **20a/20a'**, which is located at the edge of the second LOE **20b**. For a case in which the display source is an electronic element, such as a small CRT, liquid crystal display (LCD), liquid crystal on silicon (LCoS), a digital micro-

mirror device (DMD), a micro-LED array, or OLED, the driving electronics **114** for the display source might be assembled inside the back portion of the arm **112**. A power supply and data interface **116** is connectable to arm **112** by a lead **118** or other communication means including radio or optical transmission. Alternatively, a battery and miniature data link electronics can be integrated in the eyeglasses frame. The current figure is an example, and other possible head-mounted displays arrangements can be constructed, including assemblies wherein the display source is mounted parallel to the LOE plane, or in the front part of the LOE.

Additional details of this basic technology can be found in US patent 7,643,214.

FIG. 6 illustrates a method of fabricating an array of partially reflecting surfaces. The surfaces of a plurality of transparent flat plates (**422R**, shown as five exemplary plates **S1** to **S5**) are coated with the required coatings **440** and then the plates (**S1** to **S5**) are cemented together so as to create a stack form **442**. A segment **444** is then sliced off the stack form by cutting, grinding, and polishing, to create the desired array of reflecting surfaces **446**, which can then be assembled with other elements to materialize the entire LOE. More than one array **446** can be fabricate of each segment **444**, according to the actual size of the coated plates (**S1** to **S5**) and the required size of the LOE.

FIG. 7 is further details of a method for fabricating an array of selectively reflecting surfaces. The sliced lightguide **446** is cut, for example, perpendicular along both sides, along the dashed line **420A** at what will become the proximal end of the lightguide, and cut along the dashed line **420B** at what will become the distal end of the lightguide. This produces lightguide **420**. Optionally, lightguides **424** and **426** are attached respectively to the proximal and distal ends of the lightguide **420** and the combination (of **420**, **424**, and **426**) polished to produce lightguide (LOE) **429**. Alternatively, the end plates (**S1** and **S5**) can be thicker than the middle plates (**S2**, **S3**, **S4**), resulting in the sliced lightguide **446** having a structure similar to lightguide **429**, with the area of attached lightguides **424** and **426** coming from the end plates (**S1** and **S5**).

In general, each of the original transparent flat plates **422R** results in a plate of a set of coated plates **422**. Each of the plates **422** has three pairs of faces, each pair of faces parallel external surfaces of the plate. One pair of faces (shown as left and right sides in the current figure) are coated and cemented to adjoining plates to form a major axis of the lightguide (LOE). Another pair of faces (the “ends”, shown at the top and bottom in the current figure) are then respectively grinded and polished to form the major external surfaces (including the front surface **26A** and a back surface **26**. The set of coated plates includes facets created where the plates meet, thus the set

of plates includes a set of facets. The set of facets are parallel to each other, between the pair of major external surfaces (**26A**, **26**), and at a non-parallel angle relative to the major external surfaces (**26A**, **26**).

While the current figure shows an LOE with non-overlapping facets, this is not limiting, and implementations of the current invention can also be applied to overlapping facets, such as double- and triple-overlapping (not shown, refer to PCT/IL2018/050025 filed 8-January-2018, which is incorporated by reference in its entirety herein).

Detailed description – first embodiment FIG. 8 to FIG. 15

Refer now to FIG. 8, a sketch of an exemplary portion of testing for an LOE lightguide **20**. The current exemplary implementation uses an LOE, as described above with reference to FIG. 2. In operation, the incoming light ray **18** can enter the LOE **20** at the proximal end **54**. In the current test setup, display source **804** outputs light to collimating optics **806**, as is known in the art to produce light rays for testing, shown as test light rays of projected light **R**. The test light rays (projected light **R**) can be collimated, but are typically not strictly collimated, but slightly defocused to produce the projected light **R** for testing. The testing is preferably performed using monochrome light (that is, a single wavelength of light), but can be performed with any wavelength, typically in the visible spectrum. This implementation is not limiting, and other wavelengths can be used, for example, infrared. For orientation, in the current figure, the front surface **26A** is toward the incoming light rays **R**, typically at an angle as shown in the below figures (FIG. 9 to FIG. 10B). In this case, the incoming light rays are coming out of the page, at a downward angle to the front surface **26A** of the LOE **20**. The projected light **R** is typically projected toward the front surface **26A** at an oblique angle relative to the front surface **26A** as shown in the figures. This exemplary implementation is not limiting, and the projected light **R** can alternatively be projected toward the front surface **26A** normal relative to the front surface **26A**.

Refracted/reflected light rays **R'** and externally reflected rays **Re'** propagate away from the front surface **26A** out of the page, at an upward angle. This can be better understood by viewing a test set up **900** in FIG. 9 (described below).

The test light rays **R** are shown as exemplary test light rays **R1** to **R7** that traverse and exit the LOE as respective exemplary refracted/reflected light rays **R'**, shown as **R1'** to **R7'**. LOE lightguide **20** includes facets **22**, which are shown as double-lines, between the major surfaces (the

front surface **26A** and the back surface **26**). Note that the path of refracted/reflected light rays **R1'** to **R7'** is simplified for clarity. As described below, the optical path length of each of the refracted/reflected rays **R'** at the facets **22** will vary due to mismatching (inhomogeneity) between plates on either side of a facet.

5 The test light rays **R** will also be reflected by the external surface (front surface **26A**) as externally reflected light **Re'**. For clarity, only one exemplary ray of externally reflected light **R7e'** is shown in the current figure, (for clarity, obviously not at the correct angle of reflection).

Shown in the current figure are plates **422** including exemplary plate-1 **S1** having a first index of refraction n_1 , plate-2 **S2** having a second index of refraction n_2 , plate-3 **S3** having a third
10 index of refraction n_3 , plate-4 **S4** having a fourth index of refraction n_4 , plate-5 **S5** having a fifth index of refraction n_5 , and plate-6 **S6** having a sixth index of refraction n_6 . Also shown are exemplary facets: facet **F12** between plate-1 **S1** and plate-2 **S2**, facet **F23** between plate-2 **S2** and plate-3 **S3**, facet **F34** between plate-3 **S3** and plate-4 **S4**, facet **F45** between plate-4 **S4** and plate-5 **S5**, and facet **F56** between plate-5 **S5** and plate-6 **S6**. Alternatively, the plates can be described as
15 being between the facets, for example, plate-2 **S2** is between facet **F12** and facet **F23**.

Ideally, the indices of refraction of each plate should match, that is, the indices should be homogeneous: $n_1 = n_2 = n_3 = n_4 = n_5 = n_6$. However, in reality there is typically some variation between one or more indices. In an exemplary case, a first group (n_1, n_2, n_4, n_6) all have different indices, and a second (n_3, n_5) both have the same index that is also different from the index of the
20 first group. In the current case, test ray **R1** will traverse 20% of the LOE via plate-2 **S2** having refractive index n_2 , refract at facet **F23** to traverse 80% (the remaining width) via plate-3 **S3** having refractive index n_3 , reflect from back surface **26** as refracted/reflected ray **R1'** traversing 80% of the LOE via plate-3 **S3** having refractive index n_3 , refract at facet **F23** to traverse the remaining 20% of the width of the LOE via plate-2 **S2** having refractive index n_2 , and exit the LOE via the
25 front surface **26A**.

Similarly, test rays **R2-R7** will traverse the LOE as respective reflected rays **R2'-R7'** as follows (corresponding refractive indices in parenthesis for each plate, only one direction described):

R2 as **R2'** 100% via plate-3 **S3** (n_3),

30 R3 as **R3'** 80% via plate-3 **S3** (n_3) and 20% via plate-4 **S4** (n_4),

R4 as R4' 50% via plate-3 S3 (n3) and 50% via plate-4 S4 (n4),

R5 as R5' 20% via plate-3 S3 (n3) and 80% via plate-4 S4 (n4),

R6 as R6' 100% via plate-4 S4 (n4), and

R7 as R7' 100% via plate-5 S5 (n5).

In the current case as $n_3 = n_5$, the effective optical path length, and hence the phase difference between parts of the rays reflected from the front surface **26A** and the back surface **26**, of test rays **R2** and **R7** (and corresponding refracted/reflected rays **R2'** and **R7'**) should be similar. However, the optical path length and the resulting phase difference of test rays **R2** to **R6** should vary, as the proportion of inhomogeneous substrate (plates) varies.

Refer now to FIG. 9, a high-level side-view sketch of an exemplary test setup. A test set up **900** shows an exemplary configuration for testing. For clarity in the figures, the externally reflected light **Re'** is shown using a dash-double-dot line and refracted/reflected light rays **R'** are shown using a dotted line. Display source **804** outputs light to collimating optics **806**, to produce test light rays **R**. Refracted/reflected light rays **R'**, are output from the LOE **20** and received by a capture device **1002**. Externally reflected light **Re'** is reflected from the external surface of the LOE **20** and received by the capture device **1002**. The capture device **1002** captures an image of the resultant interference signal between the refracted/reflected light rays **R'** and the externally reflected light **Re'**. For convenience, the interferogram image resulting from the refracted/reflected light rays **R'** and captured by the capture device **1002** will be referred to in this description as an interferogram, a pattern formed by wave interference, especially one represented in a photograph or diagram, as explained below.

The interference pattern is used to measure the refractive index inhomogeneity between the plates **422**. The interference pattern is between the refracted/reflected light rays (**R'**) and the externally reflected light (**Re'**). The refracted/reflected light rays (**R'**) being the result of the projected light **R** traversing, reflecting internally, and then exiting the lightguide **20** via the front surface **26A**. The externally reflected light (**Re'**) being the result of the projected light **R** reflecting from the front surface **26A**. from the front surface **26A**.

The capture device can include a variety of implementations, as convenient and sufficient for the specific desired testing. For example, the interference signal (light rays **R'**, **Re'**) can be projected onto a screen and a hand-held camera used to take a picture of the resulting interferogram.

In another example, a CCD (charge coupled device) can be positioned to directly capture the interference of the light rays (**R'**, **Re'**). The interferogram is optionally stored and processed by a processing module **1004**.

Refer now to FIG. 10A, a side-view sketch of how fringes are formed. Fringes are formed when reference light rays (projected test light rays **R**) reflecting off the first LOE **20** front surface **26A** (externally reflected light **Re'**) interfere with the corresponding refracted/reflected rays **R'** (that pass into the LOE **20**, reflect off the back surface **26**) and then pass out of the LOE **20** to a screen (capture device **1002**). In the current figure, exemplary portions of reference test light ray **R** are shown as a first portion **Ra** and a second portion **Rb**. The first portion **Ra** traverses, reflecting, refracting, and exits the LOE **20** as reflected ray **Ra'**. The second portion **Rb** reflects off of the external front surface **26a** of the LOE **20** as externally reflected ray **Rb'**. Fringes are observed when the exiting beam from the (auto-) collimator system (test rays **R**) is slightly defocused. Defocusing of the collimator **806** does not affect the relative change in fringe deviation. Greater defocusing of the collimator **806** will result in more fringes closer together, as compared to a less defocused collimator **806** that will result in relatively less fringes that are further apart. If the collimator is not defocused, the resulting generated interferogram will be a single fringe, that is, all one shade. In general, the collimator **806** is adjusted (defocused) enough to observe enough fringes to identify fringe jumps, but not adjusted (defocused) too much as the fringes will increase in number and become closer together and change in the shape of the fringe (their form) will be discernable. Generally, the external surfaces (front surface **26A** and back surface **26**) of the lightguide **20** are machined to high accuracy, and do not contribute to the fringes.

For reference, the FIG. 8 rays **R1** to **R7** are “stacked” into the page as drawn in FIG. 10A, wherein the view of the LOE **20** in current FIG. 10A is from the left side of the LOE **20** of FIG. 8.

Refer now to FIG. 10B, a detailed sketch of interference. The appearance of the signal on the screen (captured image) is an indication of the optical path difference between the externally reflecting rays **Re'** (dash-double-dot line) and reflected/refracted rays **R'** (dotted line) rays of the current figure. The current figure is an example of the refraction at the interface between air and S-TIM8 glass ($n = 1.5955$), hence the refraction angle of 26.3° inside the LOE **20**.

Refer now to FIG. 11, a sketch of producing an overall pattern for various regions of the LOE. As the fringe pattern includes interference between light which does not pass through the LOE **20** (externally reflected light **Re'**) with light that does pass through the LOE **20** (refracted/reflected light rays **R'**), the overall pattern reveals comparative information for rays that

pass through various regions of the LOE **20**, i.e. different plates. In the current figure, plates **S11**, **S12**, **S13** have respective refractive indices (n_1 , n_2 , n_1). This is depicted in the current figure wherein ray paths **1101** and ray path **1102** traverse the LOE **20** through different plates of potentially different refractive indices. The current figure shows these rays (**1101**, **1102**). In the orientation of previous Fig. 10B, ray paths **1101** and ray paths **1102** overlap, and are shown as reflected/refracted rays **R'**. The resulting interferogram **1200** shows optical path differences between the externally reflecting rays **Re'** and the reflected/refracted **1101** / **1102** rays as bands **B**, or "fringes" between black or dark areas **D**. Three exemplary bands are shown, **B1**, **B2**, **B3** between four exemplary dark areas, **D1**, **D2**, **D3**, **D4**. In a case where a helium-neon red laser source is used, the bands **B** will be red color between black areas **D**. Alternatively, grayscale or black/white images can be used, such as the current black areas **D** and white fringes **B** of the current figure.

A fringe (band **B**) is a region extending from the center of a dark area of an interferogram, through a light region and back to the center of the next dark region. For example, fringe **B1** is a light region between dark area **D1** and dark area **D2**. A light region occurs when rays from two distinct paths coincide and are in-phase with each other. That is, the rays' optical path lengths are separated by a whole number of wavelengths and constructive interference occurs. Accordingly, a region when rays from two distinct paths coincide and are out-of-phase with each other, that is, separated by $(n+1/2)$ wavelengths, destructive interference occurs and the region will be dark. Therefore, the resultant fringe pattern is a direct indicator of relative path length in the LOE, which is in turn an indicator of change in refractive index.

In the current figure, the fringes are generally horizontal bands, corresponding to the alignment along a major axis of the LOE **20**. Two slopes are shown: Slope **1130** corresponding to the area of the LOE **20** for plate **S11** and **S12**, and slope **1132** corresponding to the area of the LOE **20** for plate **S12** and plate **S13**. The slopes in the interferogram **1200** represent areas where the ray path (reflected/refracted rays **R'**, as described in reference to FIG. 8) is gradually split between two plates (varying proportions of n_1 and n_2 in the current figure). The line marked as **1211** defines the characteristics of n_1 (plate **S11** having refractive index n_1 , where a ray traverses the LOE via 100% of plate **S11**, that is, 100% n_1). Similarly, the line marked as **1212** defines the characteristics of n_2 (plate **S12** having refractive index n_2 , where a refracted/reflected ray traverses the LOE via 100% of plate **S12** / 100% n_2).

If there is a difference between the refractive indices of the plates (**S11**, **S12**, **S13**), then the **1101** / **1102** rays will have a difference optical path length (OPL) and the change in phase will be reflected in a deviation in the fringe pattern. This difference between characteristics of (typically adjoining) plates is referred to as a “fringe jump”. The fringe jump can be seen in the interferogram **1200** by a vertical difference between one portion of a fringe at a first horizontal location and another portion of a fringe at another horizontal location. A non-limiting example can be seen from exemplary fringe **B2** having a fringe jump **1114**. In general, the fringes (fringe sizes, fringe widths) will all be the same size as shown by fringe size **1116**. In general, the fringe size and fringe jumps can be measured from any point in the fringe, for example, from a mid-point of the dark area **D** or the mid-point of a fringe **B**. In the current example, the fringe jump **1114** is measured from a first portion having a first point **1111** at line **1211** to a second portion having a second point **1112** at line **1212**. In this case, the optical path length difference from plate **S11** to plate **S12** results in approximately a difference between fringes of one fringe (a fringe jump **1114** of one fringe **1116**).

As an exemplary calculation, what would be the difference in fringes for adjacent plates having an inhomogeneity of 1×10^{-4} ?

The refracted angles inside the materials are calculated from the following:

$$\sin\theta_1 = \frac{\sin 45^\circ}{n_1} \quad \sin\theta_2 = \frac{\sin 45^\circ}{n_2}$$

where θ_1 is the refracted angle at plates of n_1 and θ_2 is the refracted angle at plates of n_2 .

The difference in optical path length between the paths in these adjacent plates would then be:

$$\Delta \text{Optical path} = 2 \frac{d}{\cos\theta_2} n_2 - 2 \frac{d}{\cos\theta_1} n_1 = m\lambda$$

Where d is the slice thickness (width of LOE **20**), m is the number of resultant fringe jumps, and λ is the wavelength of the test light rays R .

For the parameters $n_1 = 1.5955$ $n_2 = 1.5956$ $d = 1.5\text{mm}$ $\Delta n = 1 \cdot 10^{-4}$

$$\lambda = 632.8 \cdot 10^{-9}$$

$$\rightarrow m = 0.40$$

Therefore, refractive index inhomogeneity in plates of 1×10^{-4} would manifest in a fringe jump of 0.40 fringes.

Refer now to FIG. 12, a photograph of a good fringe pattern. In the current figure, the interferogram shows a maximum fringe jump is less than 0.3 of a fringe. This indicates an inhomogeneity of less than 1×10^{-4} .

Refer now to FIG. 13, a photograph of a bad fringe pattern. In this example, the “bad” fringe pattern indicates an inhomogeneity greater than the maximum allowed inhomogeneity for the particular application of the device under test (LOE 20). On the left-hand side of the interferogram of the current figure, fringe jumps of almost a whole fringe can be seen. This corresponds to inhomogeneity of approximately 2×10^{-4} .

Refer now to FIG. 14, a photograph of a really bad fringe pattern. This significant inhomogeneity results in noticeably visible jumps in a pattern viewed using the LOE 20 of this test.

The vertical lines 1400 drawn on the current figure denote the facet boundaries. The fringe separation, denoted by dots 1402, represents the maximum inhomogeneity. In the current interferogram, each of the six plates has noticeable differences in refractive index. In the worst case, the fringe jump is two whole fringes (fringe jump 1406 between horizontal lines 1404). This corresponds to an inhomogeneity of approximately 5×10^{-4} .

DETERMINING FRINGE JUMPS

Determining deviation between one or more portions of the fringes and another one or more portions of the fringes, corresponds to refractive index inhomogeneity between indices of refraction of the plates. The amount (number) of fringe jumps in an interferogram, and the resulting calculation of deviation (inhomogeneity), can be calculated using a variety of methods. As is known in the field of image processing, it is generally not possible for a human to perform the interpretation or calculation, and a processor (for example, processor 602) must be employed to

accomplish the task, such as handling the quantity, accuracy, and/or complexity of calculation. Using software for interferogram analysis can facilitate these steps, and is normally required for implementation of a method of analyzing an interferogram to characterize discrepancies between adjacent plates in an LOE.

5 The current implementation includes a method for a non-contact measurement technique for determining the inhomogeneity of plates within a lightguide optical element (LOE), a qualitative assessment of an interferogram to determine inhomogeneity. The deviation of the fringes can be used to calculate a pass/fail metric of inhomogeneity for the LOE.

10 The generated interferogram shows fringes, or “wiggles” resulting from the pattern of wave interference of the input test rays.

The interferometric image can be analyzed in order to extract a pass/fail metric, referred to in the context of this document as “A quantitative Facet Index Delta” (AFID) metric. The metric can be between adjacent plates, and is typically a delta over all of the plates.

15 One exemplary implementation to analyze the interferogram and determine the amount of fringe jump between fringes is to extrapolate a portion of the fringe, do a best fit to the fringe, and then compare this extrapolation to another portion of the interferogram.

20 Another exemplary implementation is to extrapolate a fringe to build (generate) an “ideal” fringe. Then a calculation is done of departure (error, jump) of an actual fringe(s) from the interferogram compared to the “ideal” fringe. The measurement of departure can be in portions of a fringe. Then the measure of departure can be used to calculate the inhomogeneity of the LOE 20.

By way of example, the image (interferogram) is analyzed in a sequence that could include all or a subset of the steps of:

- 25 1. Analyze the interferogram to determine axes of the interferogram, i.e. direction of uniform path difference for a perfect LOE.
2. Image rotation transformation (this step can be done by image processing or by optical means).

3. Split the interferogram into N discrete signal arrays orthogonal to fringes, whereby N is significantly larger than the number of facets in the LOE, for example, an order of magnitude larger.

4. Calculate phase of signal arrays n=1 to N, by use of known phase extraction algorithms such as

- a. 3 or 4 bucket method,
- b. wavelet transform, or
- c. other known methods.

5. Plot phase as a function of n and determine maximum phase difference between overall maxima and minima in phase plot, i.e. calculate AFID metric.

In another embodiment, the AFID metric is calculated according to steps 1 to 4 above, and then pair wise calculated for each pair of adjacent slabs in an LOE.

While the current embodiment has been described with regard to an LOE lightguide **20**, it is foreseen that based on this description, the disclosed techniques can be used to test other devices, such as devices including multiple plate construction and/or combinations of refractions.

FIG. 15 is a high-level partial block diagram of an exemplary system **600** configured to implement the processing module **1004** of the present embodiment. System (processing system) **600** includes a processor **602** (one or more) and four exemplary memory devices: a random-access memory (RAM) **604**, a boot read only memory (ROM) **606**, a mass storage device (hard disk) **608**, and a flash memory **610**, all communicating via a common bus **612**. As is known in the art, processing and memory can include any computer readable medium storing software and/or firmware and/or any hardware element(s) including but not limited to field programmable logic array (FPLA) element(s), hard-wired logic element(s), field programmable gate array (FPGA) element(s), and application-specific integrated circuit (ASIC) element(s). Any instruction set architecture may be used in processor **602** including but not limited to reduced instruction set computer (RISC) architecture and/or complex instruction set computer (CISC) architecture. A

module (processing module) **614** is shown on mass storage **608**, but as will be obvious to one skilled in the art, could be located on any of the memory devices.

Mass storage device **608** is a non-limiting example of a non-transitory computer-readable storage medium bearing computer-readable code for implementing the measuring technique methodology described herein. Other examples of such computer-readable storage media include read-only memories such as CDs bearing such code.

System **600** may have an operating system stored on the memory devices, the ROM may include boot code for the system, and the processor may be configured for executing the boot code to load the operating system to RAM **604**, executing the operating system to copy computer-readable code to RAM **604** and execute the code.

Network connection **620** provides communications to and from system **600**. Typically, a single network connection provides one or more links, including virtual connections, to other devices on local and/or remote networks. Alternatively, system **600** can include more than one network connection (not shown), each network connection providing one or more links to other devices and/or networks.

System **600** can be implemented as a server or client respectively connected through a network to a client or server.

Note that a variety of implementations for modules and processing are possible, depending on the application. Modules are preferably implemented in software, but can also be implemented in hardware and firmware, on a single processor or distributed processors, at one or more locations. The above-described module functions can be combined and implemented as fewer modules or separated into sub-functions and implemented as a larger number of modules. Based on the above description, one skilled in the art will be able to design an implementation for a specific application.

Note that the above-described examples, numbers used, and exemplary calculations are to assist in the description of this embodiment. Inadvertent typographical errors, mathematical errors, and/or the use of simplified calculations do not detract from the utility and basic advantages of the invention.

To the extent that the appended claims have been drafted without multiple dependencies, this has been done only to accommodate formal requirements in jurisdictions that do not allow such multiple dependencies. Note that all possible combinations of features that would be implied by

rendering the claims multiply dependent are explicitly envisaged and should be considered part of the invention.

It will be appreciated that the above descriptions are intended only to serve as examples, and that many other embodiments are possible within the scope of the present invention as defined in

5 the appended claims.

WHAT IS CLAIMED IS:

1. A method for measuring refractive index inhomogeneity comprising the steps of:
 - (a) projecting projected light (R) onto a front surface (26A) of a lightguide (20), said lightguide (20) including:
 - (i) a first pair of external surfaces parallel to each other, said external surfaces including said front surface (26A) and a back surface (26), and
 - (ii) a set of coated plates (422), said set of plates (422):
 - (A) parallel to each other,
 - (B) between said first pair of external surfaces, and
 - (C) at a non-parallel angle relative to said first pair of external surfaces, and
 - (iii) each of said plates (422) having a corresponding index of refraction (n), and
 - (b) capturing an interferogram image (1200) of an interference pattern to measure the refractive index inhomogeneity between said plates (422), said interference pattern between refracted/reflected light rays (R') and externally reflected light (Re'),
 - (i) said refracted/reflected light rays (R') being the result of said projected light (R) traversing, reflecting internally, and then exiting said lightguide (20) via said front surface (26A) and
 - (ii) said externally reflected light (Re') being the result of said projected light (R) reflecting from said front surface (26A).
2. The method of claim 1 wherein said projecting is selected from the group consisting of:
 - (a) at an oblique angle relative to said front surface (26A), and
 - (b) normal relative to said front surface (26A).
3. The method of claim 1 wherein said interferogram image (1200) corresponds to refractive index inhomogeneity between said indices (n) of refraction of said plates (422).
4. The method of claim 1 further including: determining deviation between one or more portions of said fringes and another one or more portions of said fringes, each of said portions

corresponding to one or more of said plates, said deviation corresponding to refractive index difference between said indices of refraction of said plates.

5. A method for determining refractive index inhomogeneity comprising the steps of:

- (a) providing an interferogram, said interferogram including one or more fringes, said interferogram generated by:
 - (i) projecting projected light (R) onto a front surface (26A) of a lightguide (20), said lightguide (20) including:
 - (A) a first pair of external surfaces parallel to each other, said external surfaces including said front surface (26A) and a back surface (26), and
 - (B) a set of plates (422), said set of plates (422):
 - (I) parallel to each other,
 - (II) between said first pair of external surfaces, and
 - (III) at a non-parallel angle relative to said first pair of external surfaces, and
 - (C) each of said plates (422) having a corresponding index of refraction (n), and
 - (ii) capturing an interferogram image (1200) of an interference pattern to measure the refractive index inhomogeneity between said plates (422), said interference pattern between refracted/reflected light rays (R') and externally reflected light (Re'),
 - (A) said refracted/reflected light rays (R') being the result of said projected light (R) traversing, reflecting internally, and then exiting said lightguide (20) via said front surface (26A) and
 - (B) said externally reflected light (Re') being the result of said projected light (R) reflecting from said front surface (26A), and
- (b) determining deviation between one or more portions of said fringes and another one or more portions of said fringes, each of said portions corresponding to one or more of said plates, said deviation corresponding to refractive index inhomogeneity between said indices of refraction of said plates.

6. The method of claim 5 wherein each of said portions of said fringes corresponds to one of said plates.

7. The method of claim 5 wherein said deviation is between adjacent said plates.

8. The method of claim 5 wherein said deviation is across multiple said plates.

9. The method of claim 5 wherein said deviation is across all said plates.

10. The method of claim 5 wherein said determining deviation includes determining how many fringe jumps are in said interferogram.

11. The method of claim 5 further including a step of calculating a pass/fail metric based on said deviation.

12. The method of claim 5 wherein said deviation is determined using at least one technique selected from the group consisting of:

- (a) analyzing said interferogram to determine axes of said interferogram,
- (b) rotating and/or transforming said interferogram,
- (c) splitting said interferogram into N discrete signal arrays orthogonal to said fringes, whereby N is significantly larger than the number of facets in the LOE, and
- (d) calculating a phase of signal arrays n=1 to N, by use of a phase extraction algorithm selected from the group consisting of:
 - (i) three or four bucket method, and
 - (ii) wavelet transform.

13. The method of claim 5 wherein a pass/fail metric is derived from said deviation determined over an entirety of said interferogram, and then other pass/fail metrics are derived from deviations between adjacent said plates.

14. The method of claim 5 wherein said deviation is determined by:

- (a) splitting said interferogram into N discrete signal arrays orthogonal to said fringes,
- (b) calculating a phase of said signal arrays $n=1$ to N, by use of a phase extraction algorithm, and
- (c) plotting said phase as a function of n and determining maximum phase difference between overall maxima and minima in said phase plot.

15. The method of claim 5 wherein said deviation is determined:

- (a) using a portion of one of said fringes,
- (b) doing a best fit extrapolation to said portion of one of said fringes, and
- (c) comparing said extrapolation to another portion of said fringes.

16. The method of claim 5 wherein said deviation is determined by:

- (a) extrapolating one of said fringes to generate an ideal fringe,
- (b) calculating a departure of an actual one of said fringes from said ideal fringe.

17. The method of any of the above claims wherein said projected light is collimated light that is slightly defocused.

18. The method of any of the above claims wherein said projected light is monochrome light.

19. The method of any of the above claims wherein said projected light is in the visible spectrum.

20. A system for measuring refractive index inhomogeneity, the system comprising

- (a) a display source (804),
- (b) collimating optics (806),
- (c) a lightguide (20) including:
 - (i) a first pair of external surfaces parallel to each other, said external surfaces including said front surface (26A) and a back surface (26), and
 - (ii) a set of plates (422), said set of plates (422):

- (A) parallel to each other,
 - (B) between said first pair of external surfaces, and
 - (C) at a non-parallel angle relative to said first pair of external surfaces,
- and
- each of said plates (422) having a corresponding index of refraction (n), and
- (d) a capture device (1002) deployed to capture an interferogram image of an interference pattern (1200) to measure the refractive index inhomogeneity between said plates (422), said interference pattern between refracted/reflected light rays (R') and externally reflected light (Re'),
 - (i) said refracted/reflected light rays (R') being the result of said projected light (R) traversing, reflecting internally, and then exiting said lightguide (20) via said front surface (26A) and
 - (ii) said externally reflected light (Re') being the result of said projected light (R) reflecting from said front surface (26A).

21. The system of claim 20 further comprising a processing system containing one or more processors (600), said processing system (600) being configured to determining deviation between one or more portions of said fringes and another one or more portions of said fringes, each of said portions corresponding to one or more of said plates, said deviation corresponding to refractive index inhomogeneity between said indices of refraction of said plates.

22. A system for determining refractive index inhomogeneity, the system comprising a processing system (600) containing one or more processors, said processing system being configured to:

- (a) process an interferogram, said interferogram including one or more fringes, said interferogram generated by:
 - (i) projecting projected light (R) onto a front surface (26A) of a lightguide (20), said lightguide (20) including:
 - (A) a first pair of external surfaces parallel to each other, said external surfaces including said front surface (26A) and a back surface (26),
 - and
 - (B) a set of plates (422), said set of plates (422):

- (I) parallel to each other,
 - (II) between said first pair of external surfaces, and
 - (III) at a non-parallel angle relative to said first pair of external surfaces, and
- (C) each of said plates (422) having a corresponding index of refraction (n), and
- (ii) capturing an interferogram image (1200) of an interference pattern to measure the refractive index inhomogeneity between said plates (422), said interference pattern between refracted/reflected light rays (R') and externally reflected light (Re'),
 - (A) said refracted/reflected light rays (R') being the result of said projected light (R) traversing, reflecting internally, and then exiting said lightguide (20) via said front surface (26A) and
 - (B) said externally reflected light (Re') being the result of said projected light (R) reflecting from said front surface (26A), and
- (b) determine deviation between one or more portions of said fringes and another one or more portions of said fringes, each of said portions corresponding to one or more of said plates, said deviation corresponding to refractive index inhomogeneity between said indices of refraction of said plates.

Fig.1.

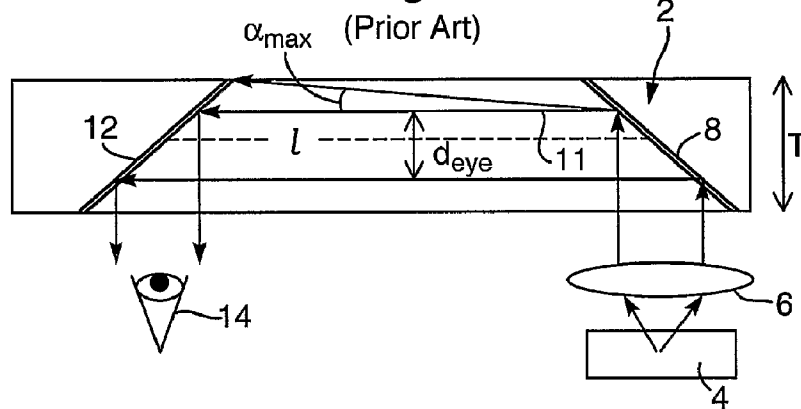


Fig.2.

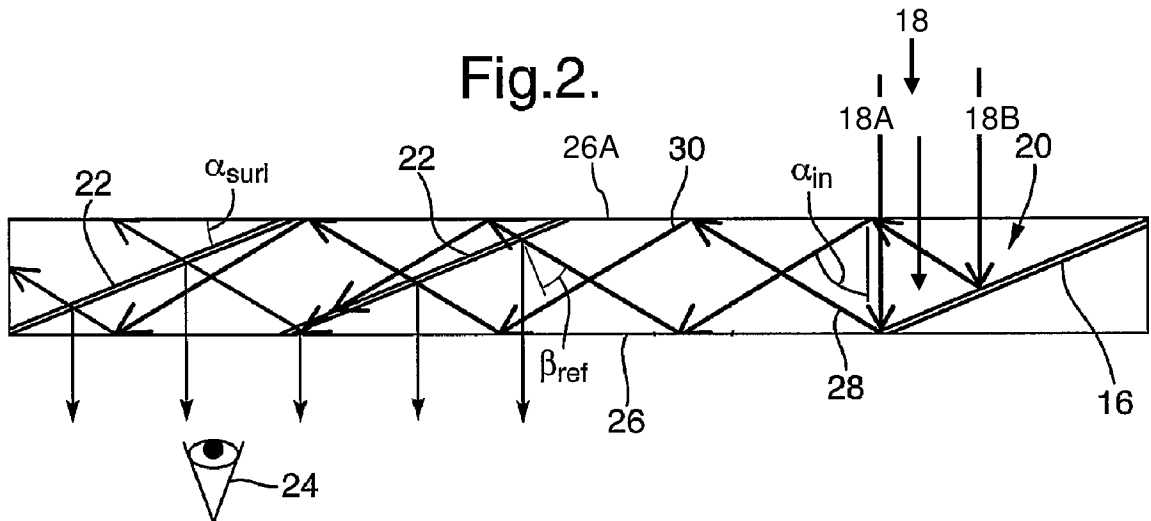


Fig.3A.

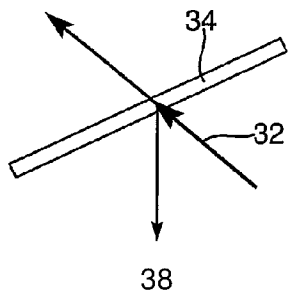


Fig.3B.

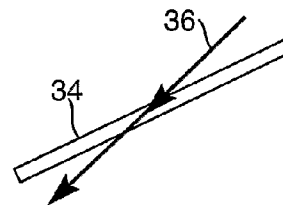


FIG. 4

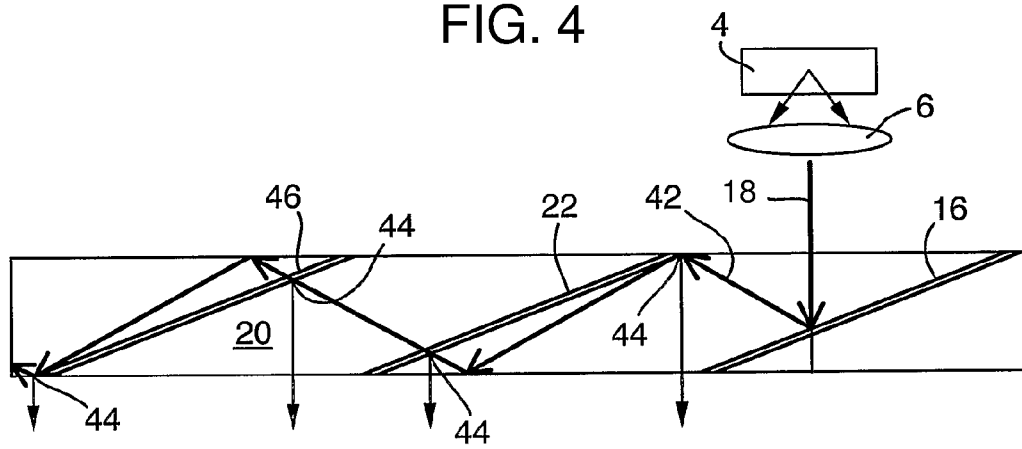


FIG. 5

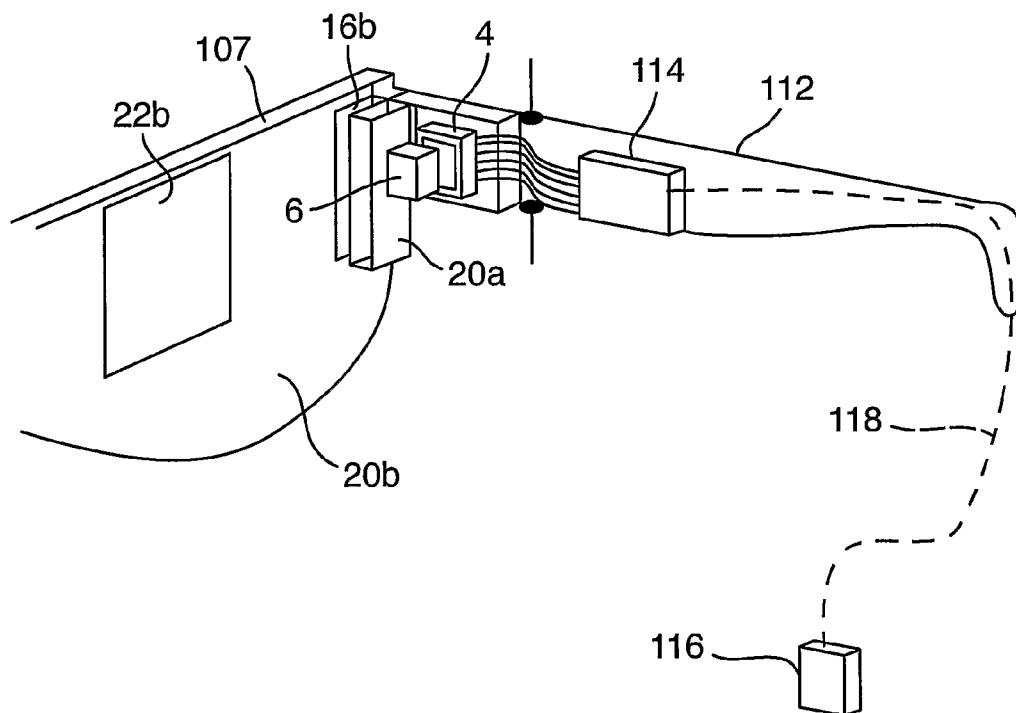


FIG. 6

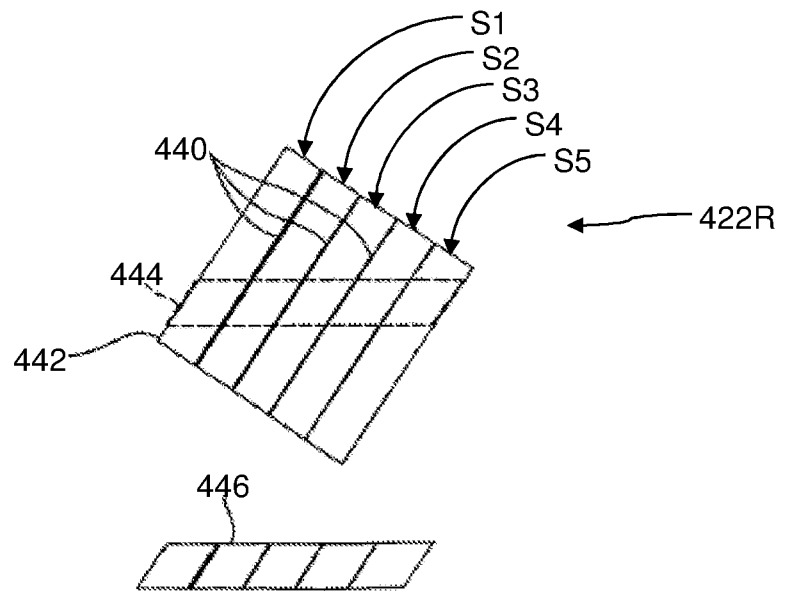
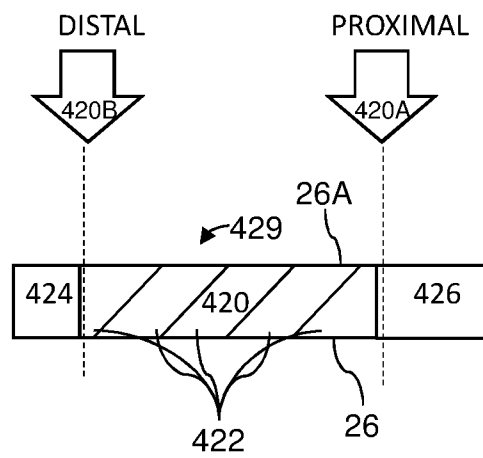


FIG. 7



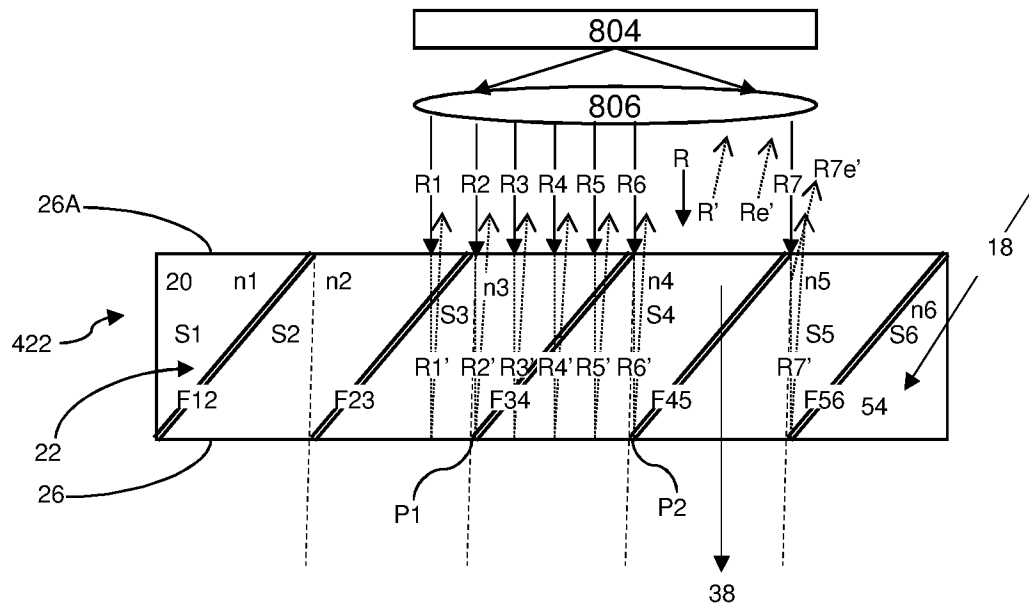
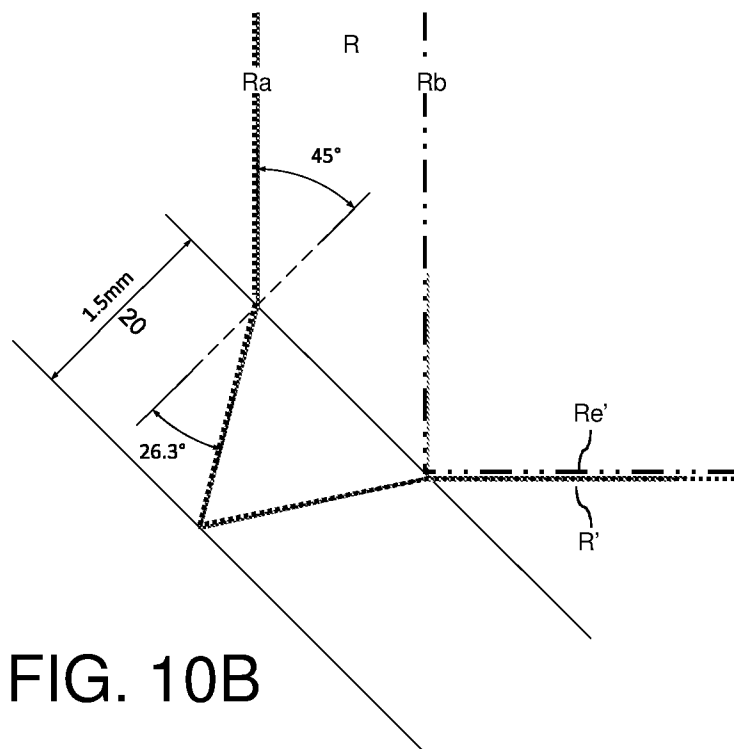
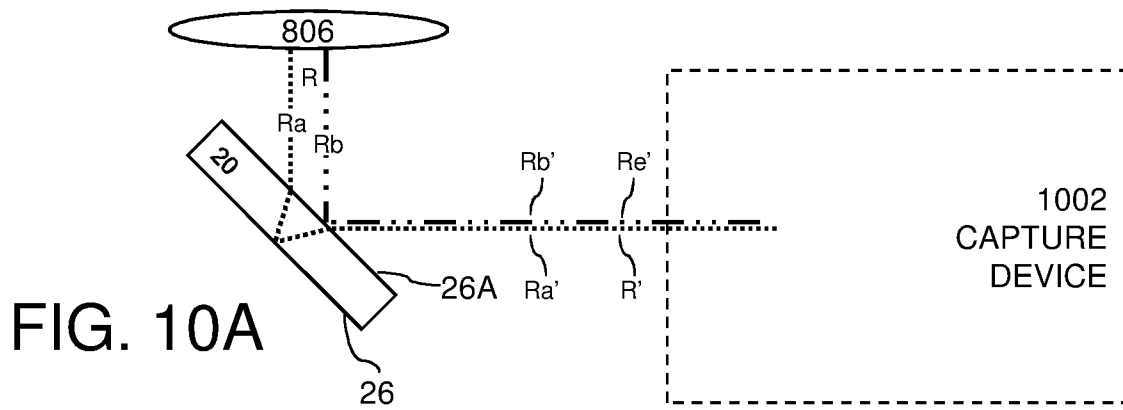
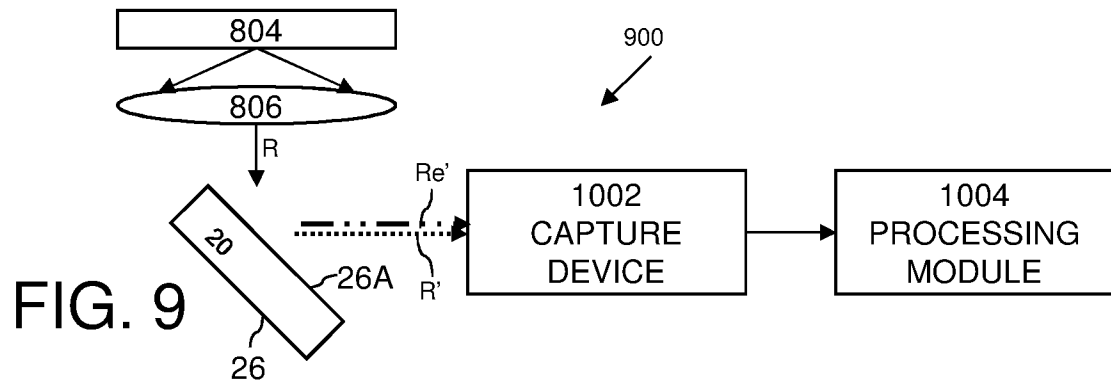


FIG. 8



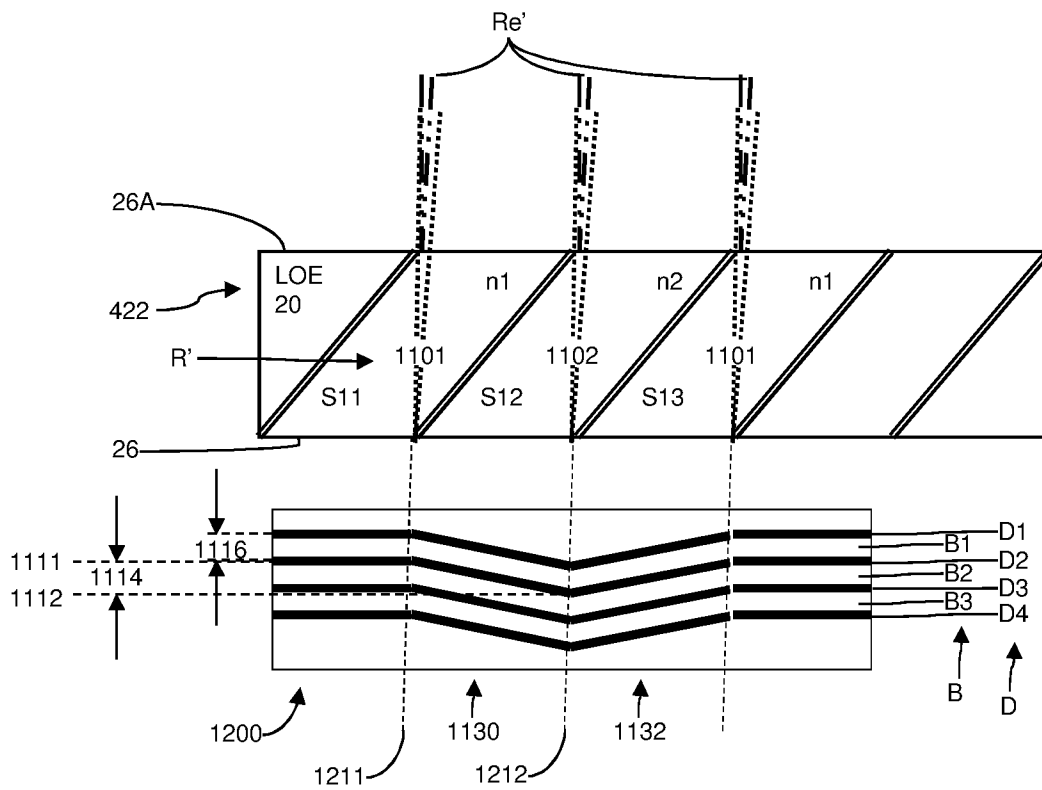


FIG. 11

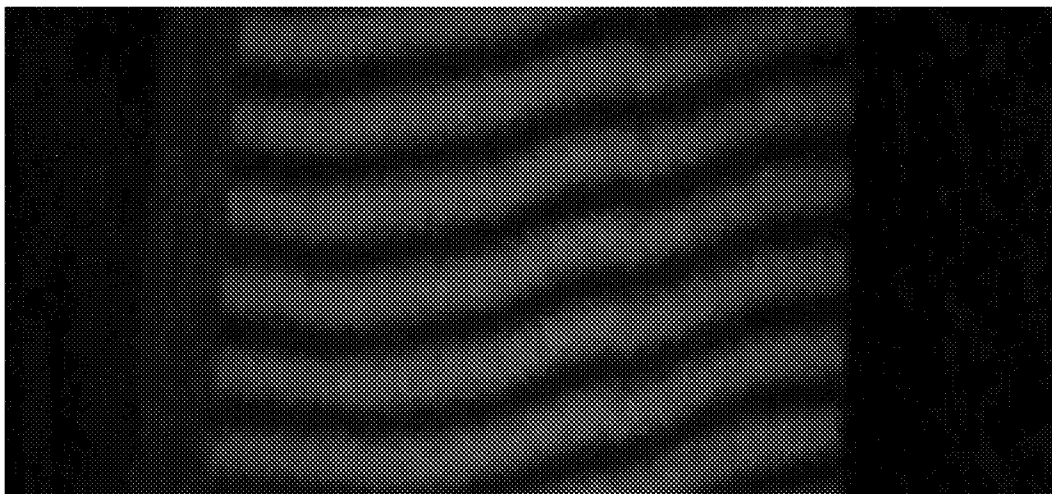


FIG. 12

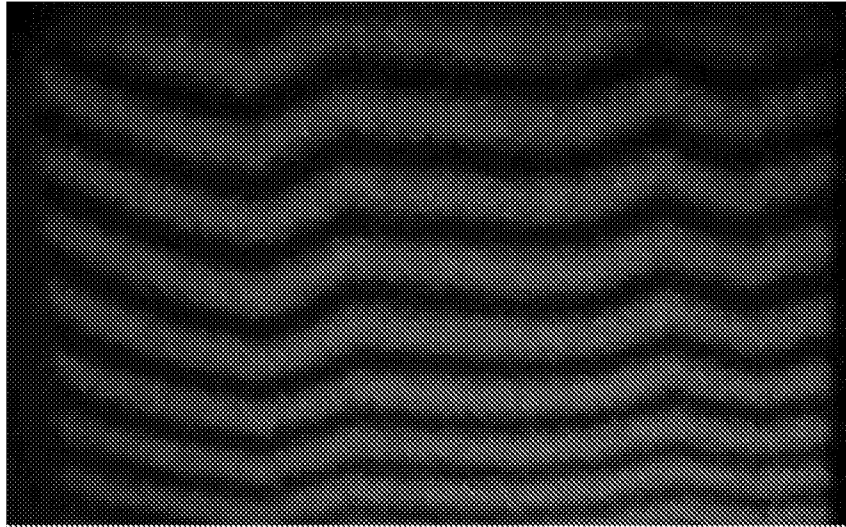


FIGURE 13

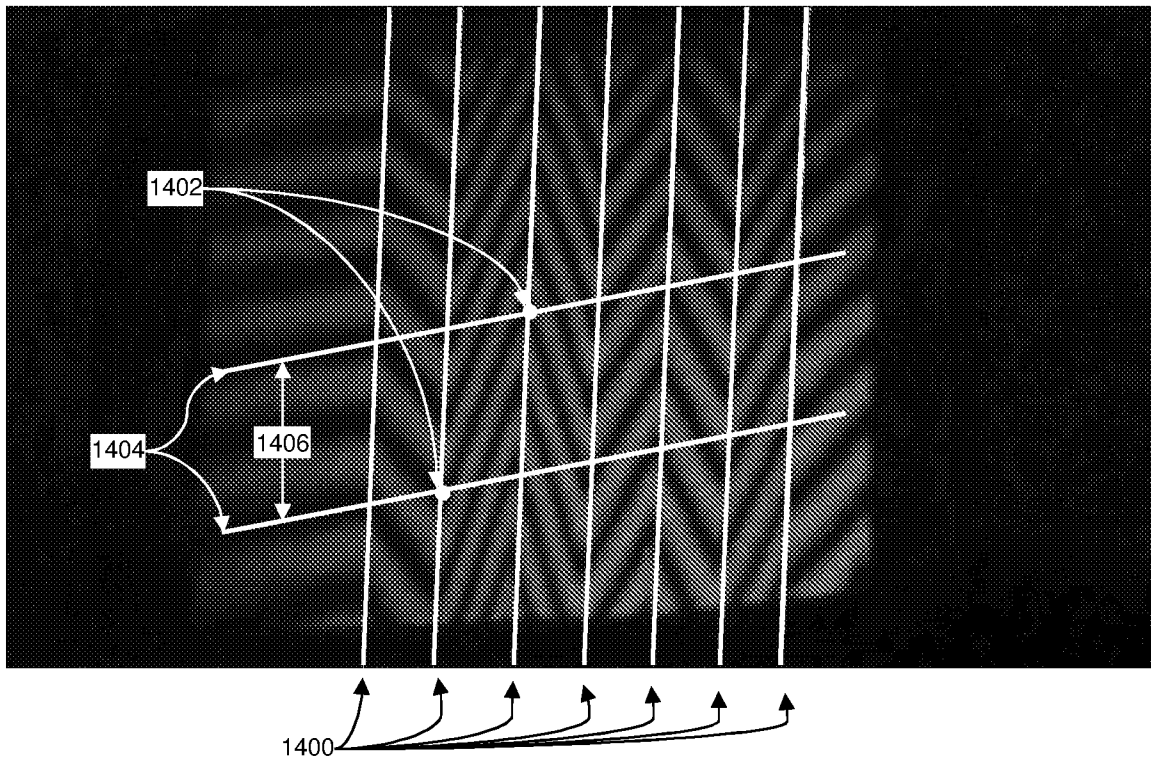


FIGURE 14

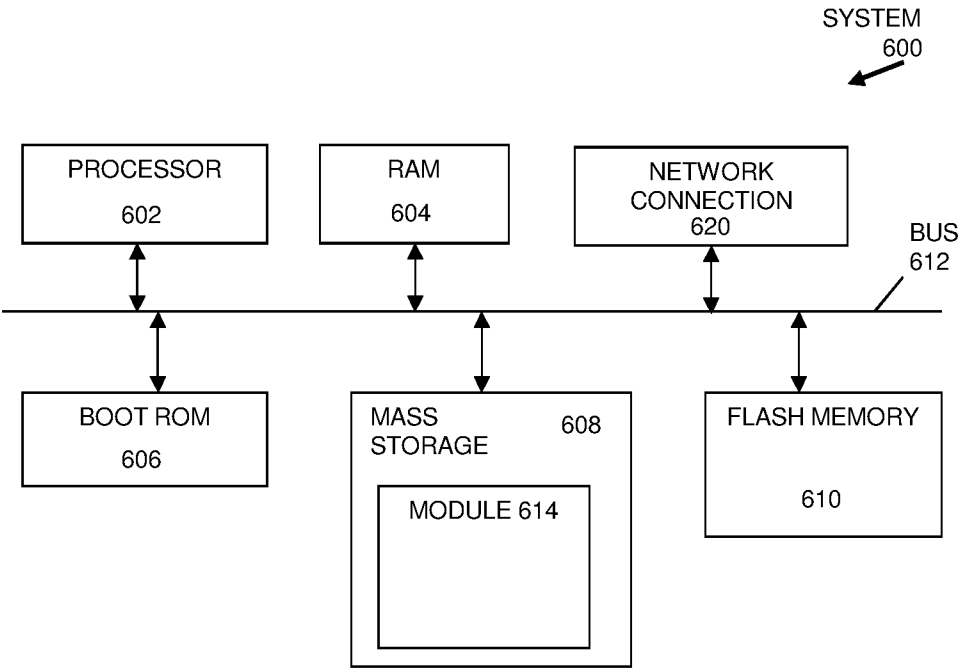


FIGURE 15

INTERNATIONAL SEARCH REPORT

International application No.

PCT/IB2019/055207

A. CLASSIFICATION OF SUBJECT MATTER

IPC (20190101) G01N 21/45, G01M 11/02

CPC (20130101) G01N 21/45, G01M 11/02

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

IPC (20190101) G01N 21/45, G01M 11/02

CPC (20130101) G01N 21/45, G01M 11/02

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practicable, search terms used)

Databases consulted: Esp@cenet, Orbit

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y	JP 2013231652 A FK KOGAKU KENKYUSHO KK 14 Nov 2013 (2013/11/14) The whole document	1-22
Y	US 2009122414 A1 LUMUS LTD 14 May 2009 (2009/05/14) The whole document	1-22
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Further documents are listed in the continuation of Box C.

☒

See patent family annex.

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Date of the actual completion of the international search

10 Oct 2019

Date of mailing of the international search report

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International application No.
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